



Attorney's Docket No. 5308-157IP2

PATENT

1762
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Das et al.

Confirmation No.: 3570

Serial No.: 10/045,542

Group Art Unit: 1762

Filed: October 26, 2001

Examiner: Michael. E. Barr

For: METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE
LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: September 21, 2004

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

UNDER 37 C.F.R. § 1.97(b)

Sir:

Attached is a list of documents on form PTO-1449 together with copies of each identified document. This Information Disclosure Statement is submitted in accordance with 37 C.F.R. § 1.97(c), before final Office Action or Allowance, whichever is earlier.

In accordance with the requirements of 37 C.F.R. § 1.97(c)(2), a check for the \$180.00 fee specified in 37 C.F.R. § 1.17(p) is enclosed. This amount is believed to be correct; however, the Commissioner is authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-0220.

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Respectfully submitted,

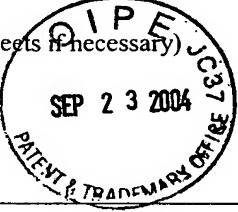
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on September 21, 2004.

Traci A. Brown

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5308-157IP2		Serial No. 10/045,542	
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)							
				Applicants: Das et al.			
				Filing Date: October 26, 2001		Group 1762	
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	1	Wang et al. "The Effects of NH ₃ Plasma Passivation on Polysilicon Thin-Film Transistors," <i>IEEE Electron Device Letters</i> , Vol. 16, No. 11, November 1995, pp. 503-5.					

 EXAMINER
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DATE CONSIDERED

Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.